Application No. 10/518,197 Paper Dated: March 28, 2008

In Reply to USPTO Correspondence of September 28, 2007

Attorney Docket No. 1217-045623

AMENDMENTS TO THE SPECIFICATION

Please amend the Abstract appearing on p. 44 as follows:

-- A silicon production reactor eemprising including a reaction vessel and heating means element, said the reaction vessel eemprising has a vertically extending wall and a space surrounded by the wall, said the heating means element being capable of heating at least a part, including lower end portion, of the wall's surface facing the space to a temperature of not lower than the melting point of silicon, said the silicon production reactor being adapted to flow raw gas for silicon deposition from an upper part of the space of the reaction vessel toward a lower part thereof, characterized in that the space of the reaction vessel is of slit form in cross-sectional view. This silicon production reactor is capable of attaining improvement with respect to problems encountered at apparatus sealeup scale-up, such as decrease of reactivity of raw gas and generation of by-products, thereby accomplishing a striking enhancement of production efficiency. --